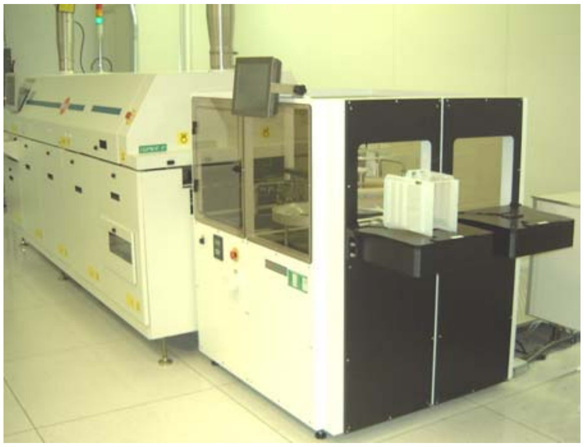
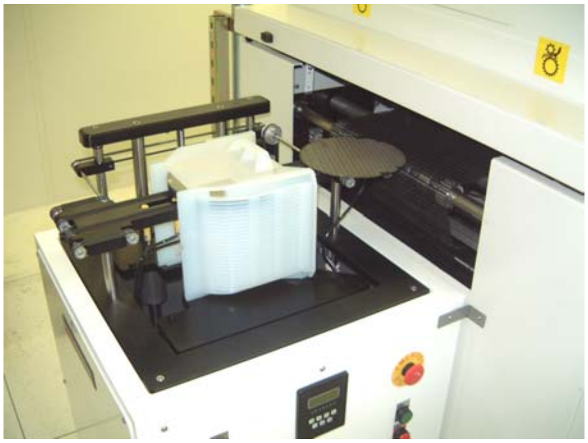
SCIENTIFIC MOTION

Wafer Bumping Line



Spin Coater Integrated with Reflow Oven



Indexer Integrated with Reflow Oven

- Scientific Motion Flux Dispensers, Wafer Cleaners, Robotic Wafer Handling Systems, and Indexers are seamlessly integrated with all types of reflow ovens.
- Processes wafer sizes from 100mm through 300mm.
- Modular design allows up to 2 FOUP load ports or 2 cassette stations or combination of both.
- Wafer size, lot size, and status are communicated between process equipment on both sides of the reflow oven via Ethernet.
- SMEMA communication between process equipment and reflow oven ensures reliable process flow.
- A 25 wafer buffer on the receive end of the reflow oven is utilized for reliable wafer handoff.
- Emergency Machine Off (EMO) can be integrated between the reflow oven and process equipment for added safety.